

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant : Masaharu Nagai et al. Art Unit : 1756  
Serial No. : 10/694,986 Examiner : Deborah Chacko Davis  
Filed : October 29, 2003 Conf. No. : 5334  
Title : METHOD FOR REMOVING RESIST PATTERN AND METHOD FOR  
MANUFACTURING SEMICONDUCTOR DEVICE

Mail Stop Amendment  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

REPLY TO ACTION OF OCTOBER 3, 2006

Please amend the above-identified application as follows:

Amendments to the Claims begin on page 2.

Remarks begin on page 8.